



Session Title:	[WE1] Advanced Lithography for Future Optical Devices I
Session Date:	November 22 (Wed.), 2023
Session Time:	08:30-10:10
Session Room:	Room E (Sidney Room, 2F)
Session Chair:	Prof. Myungki Kim (Korea Univ., Korea)

[WE1-1] [Invited] 08:30-09:00

Dielectric Metasurfaces for Optical Field Imaging Devices and Optimized Photonic Devices

Hyoungchan Kwon (KIST, Korea)

[WE1-2] [Invited] 09:00-09:30

On-Chip Ultra-Low-Loss Optical Components for Mid-Infrared Photonics

Hansuek Lee, Daewon Suk, Kiyong Ko, Soobong Park, Dohyeong Kim, Seong Cheol Lee (KAIST, Korea), Kwang-Hoon Ko (KAERI, Korea), Fabian Rotermund (KAIST, Korea), and Duk-Yong Choi (Australian Nat'l Univ., Australia)

[WE1-3] 09:30-09:50

Fabrication of Tunable Metasurface Platform for Hologram Display

Soo-Jung Kim, Doa Kim, and Sung-Hoon Hong (ETRI, Korea)

[WE1-4] 09:50-10:10

Multilayered All-Polymer Metasurfaces on Optical Fiber Apex Using Micropunching Method

Moohyuk Kim, Nu-Ri Park (Korea Univ., Korea), Minseok Jeon (KIST, Korea), and Myung-Ki Kim (Korea Univ., Korea)